AMENDMENTS TO THE SPECIFICATION

1. Please replace the title with the following:

PROCESS FOR DEPOSITING METALS AND CERAMICS ONTO UNPLATED ZINC OR ZINC ALLOY SUBSTRATES USING PHYSICAL VAPOR DEPOSITION

2. Please amend the paragraph under the heading "Cross-Reference to Related Applications," as introduced in the Preliminary Amendment dated January 2, 2004, as follows:

This application is a continuation of and claims the priority benefit under 35 U.S.C. § 120 of U.S. Application No. 09/781,378 filed on February 12, 2001 and now abandoned. The contents of this application are fully incorporated herein by reference.

3. Please add the following heading and paragraph after the section titled "Cross-Reference to Related Applications".

FIELD OF THE INVENTION

This invention relates to the process of forming films of decorative metals and ceramics on zinc and zinc alloy substrates. More particularly, the invention relates to the deposition of such films directly onto zinc and zinc alloys utilizing physical vapor deposition (PVD) technology.

4. Please amend the first paragraph after the section titled "Background of the Invention" as provided below.

This invention relates to the process of forming films of decorative metals and ceramics on zinc and zinc alloy substrates. More particularly, the invention relates to the deposition of such films directly onto zinc and zinc alloys utilizing physical vapor deposition (PVD)

Appl. No. 10/751,305 Amdt. dated September 7, 2005

technology. Reactors for conducting PVD manufacturing operations on substrates are well known and are widely used in the manufacture of decorative hardware coatings and other products utilizing cathodic arc and direct thermal evaporation sources. Substrates are defined as any object or product placed inside of a vacuum reactor, and onto which, a film is to be deposited in the reactor.

5. Please replace the Abstract with the one provided on the following page.